



**ICTF-15**  
**15th International Conference**  
**on Thin Films, 2011**

Conference Site : Kyoto TERRSA



organized by  The Vacuum Society of Japan  
 on behalf of  IUVSTA

***Message to you from Chair, Prof. Osamu TAKAI !!***

The 15th International Conference on Thin Films (ICTF-15) will be held in the KYOTO TERRSA, Japan on November 8-11, 2011. This conference will bring together researchers from around the world who have interests in thin films following the priority subjects;

- **To discuss and share** the recent **achievements** and **innovations** in the fields of advanced thin film research and technology in the world.
- **To promote** interests in the fundamental of thin films and the application of various kinds of advanced thin films, especially related with the **nano-**, the **photonic-**, the **information-**, the **bio-** and the **automobile-**materials & technologies.
- **To facilitate** interactions between researchers from industry, national laboratory and academia for the future **international collaborations**.
- **To encourage students, young** scientists and young engineers to pursue future professional careers in the materials research, engineering and technology.

**Topics**

**[T1] Fundamentals of Thin Film Growth and Epitaxy**

- Real time thin film growth studies
- Surface chemistry of structure formation in multi-component thin films
- Surface chemistry for thin films
- Self organized growth
- Dynamics and reaction kinetics of thin film growth
- Biosurfaces and biointerfaces related to thin film growth

**[T2] Nanostructured Growth**

- Growth on templated surfaces
- Growth of nanowires and nanorods
- Micro- and nano-architectures and functions
- Formation of micro- and nano-templates

**[T3] Advances in Deposition Techniques**

- Physical vapor deposition (PVD)
- Chemical vapor deposition (CVD)
- Atomic layer deposition (ALD)
- High power impulse magnetron sputtering (HIPIMS)
- Functional films on unheated substrates and flexible substrates
- Plasma processing for thin film processing
- Wet processing

**[T4] Modelling and Computer Simulation**

- Modeling of thin film growth
- Computer simulation for thin films

**[T5] Characterization and Instrumentation**

- Focused ion beams used to modify and analyze surface and interface
- Application of scanning probe techniques
- In situ real time techniques
- Imaging

**[T6] Organic Thin Films**

- Organic thin film growth
- Self-assembled monolayers (SAMs) and multilayers
- Organic nanomaterials with flexible structure and devices
- Conducting polymers
- Advanced liquid crystalline materials
- Properties of organic thin films

**[T7] Applications of Thin Films**

- Photonics
- Solar cells
- Optical devices
- Batteries
- Gas barriers
- Sensors

- Magnetic and spintronics devices
- Dielectric and ferroelectric devices
- Hard coatings
- Sustainable energy
- Data storage
- Microelectronics
- Nitride and III-V semiconductors
- Silicon and germanium based semiconductors
- Oxide films
- Transparent conducting films

**[T8] Thin Films for Future Industries**

- Thin films for bio-medical industries
- Thin films for automobile and aerospace industries
- Thin films for electronic industries
- Thin films for energy industries

**Registration Fee**

Regular		Fee	
	Before Aug. 31, 2011	40000 JPY	ca. 450 USD
	After Sep. 1, 2011	45000 JPY	ca. 500 USD
*This fee includes the abstracts and proceedings CDs and coffee break.			
Student			
	Before Aug. 31, 2011	15000 JPY	ca. 170 USD
	After Sep. 1, 2011	20000 JPY	ca. 220 USD
*This fee includes the abstracts CD and coffee break.			
Accompanying Person		10000 JPY	ca. 110 USD
Conference Reception		8000 JPY	ca. 90 USD

**Note:** New information about the payment will be announced at the website. Credit cards will be available for the payment.

**Important Date**

Deadline of Abstract Submission:

~~May 9, 2014~~  
June 30, 2011

Announcement of Acceptance:

~~June 30, 2014~~  
July 31, 2011

Advanced Registration:

August 31, 2011

**Abstract Format**

Please download abstract format from the conference website (<http://ictf15.jp/>), which is regulated with 1 page in A4 size document.

**Publication**

Manuscripts will be published in Journal of Physics: Conference Series. The total page number per a manuscript is limited to 4-6 pages for oral and poster presentations, and 4-10 pages for plenary and invited presentations.

**Note:** New information about the publication affairs will be announced at the website.

**Location**

The conference will be held at Kyoto TERRSA. Shinmachi, Kujo, Minami-ku, Kyoto, Japan. Next to JR Kyoto Station  
Tel: +81(0)75 692 3400

Fax: +81(0)75 692 3402

<http://www.kyoto-terrsa.or.jp/pdf/access-english.pdf>

**VISA**

If you need the certificates to obtain VISA, please contact secretariat for ICTF15.  
c/o Inter Group Corporation  
2-38-2, Meieki, Nakamura-ku, Nagoya, 450-0002 JAPAN

Tel: +81-52-581-3241

Fax: +81-52-581-5585

E-mail: [ictf15@intergroup.co.jp](mailto:ictf15@intergroup.co.jp)

**Note:** The certificates for VISA will be supplied after the registration.

**Website**

<http://ictf15.jp/>

**Contact**

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